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Vishnu K. Agarwal et alFILING DATE
January 15, 2002GROUP
2813

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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
yk	AA 6,204,070	03/2001	Kim			
	AB 6,207,487	03/2001	Kim et al			
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yk	AD 6,420,230	07/2002	Derderian			
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	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
yk	AM KR 2002002157A	01/2002	Korea				
	AN						
	AO						
	AP						
	AQ						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1913		Priority SERIAL NO. 09653.156		
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						Priority GROUP 2813		
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yk	AR		A.W. Ott, et al., "Atomic Layer Controlled Deposition of Al ₂ O ₃ Films Using Binary Reaction Sequence Chemistry", Applied Surface Science (107), 1996, pps. 128-136.					
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	AL						
	AM						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AN							
	AO							
	AP							
	AQ							

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